



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Chih-Wei Hsu

§ Attorney Docket No. 24061.49  
(2003-0125)

Serial No.: 10/791,930

§ Customer No. 42717

Filed: March 3, 2004

§ Group Art Unit: 2125

For: SYSTEM AND METHOD FOR  
PROCESS CONTAMINATION  
PREVENTION FOR SEMICONDUCTOR  
MANUFACTURING

§ Examiner: Kosowski, Alexander J.

**RESPONSE**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the non-final Office Action mailed March 24, 2005, please reconsider the application in light of the following amendments and remarks:

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 7 of this paper.